## Power unit controller for RF excited CO<sub>2</sub> laser

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Abstract : In this paper , we describe the design and function , application of the power unit controller for mini RF excited  $CO_2$  laser , pulse width modulation (PWM) is the convenient way to vary the laser average output power from 1 % to 100 % of maximum.

Key words: RF excitation pulse width modulation (PWM)

# RF 激励 CO<sub>2</sub> 激光器功率控制器

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摘要: 描述了小型 RF 激励 CO<sub>2</sub> 激光器的功率控制器设计、功能和应用,根据脉宽调制原理可以方便地把激光功率从1%变化到100%。 关键词: RF 激励 脉宽调制(PWM)

#### 1 Introduction

The rapid development of RF laser leading to significant application. One of the typical application is marking and cutting, material cutting and marking speed is a function of power. With processing speed directly proportional to laser out put power, for any type of laser, a power unit controller (PUC) must be provided. To effectively control output power of laser, pulse width modulation (PWM) is used to vary the average voltage applied to the RF amplifier<sup>[1,2]</sup>, which control the RF drive applied to the laser electrodes and is also a convenient way to vary the average output power from 1 % to 100 % of maximum. The laser output follows the modulation control signal with a time constant of 100µs.

In the present paper, we describe the design and function, application of the power unit controller for RF excited  $CO_2$  laser<sup>[3]</sup>. Synoptic schema of the laser is shown in Figure 1. The oscillator serves the radio-frequency of 40MHz. More information of low - power RF excited  $CO_2$  laser can get from the references [4 ~ 6] in china.



Fig. 1 Synoptic schema of RF excited laser

### 2 Description of synoptic schema

Synoptic schema of PUC is given in Figure 2. Power supply deliver 15V, 5V and - 5V DC

respectively to the circuit. A fusible 0. 5A protects the circuit. IC1 is the master clock, either set to 3, 5, 10 and 14kHz with dip switch. The output waveform is approximately square. IC2 is triggered by IC1 and provides for the 1 $\mu$ s duration "tickle signal "required for RF CO<sub>2</sub> laser. The duration of pulse can be adjusted the "tickle "signal is connected to OR gate IC3. The other input to this OR gate is from the variable duty cycle generator. Output from the OR gate goes to J3. It can drive RF CO<sub>2</sub> laser. The triangular signal delivered by master clock IC1 is then applied to a comparator through buffer IC6. The other input of the comparator is a DC signal corresponding to the selected modes (Man, ANV, Gate). The attenuator is used to attenuate the DC singal from IC7 or IC8 to a range about 2.1V at input of IC5. Whenever, the DC voltage signal exceeds the triangular signal voltage the output of IC5 goes T. T.L high level.



Fig. 2 Synoptic schema of PUC

In the ANV mode, the external control voltage of  $0 \sim 10V$  DC is buffered by IC9 to generate a high impedance input and is then applied to the input error amplifier IC8 which compares control voltage signal to fixed reference voltage. The error is amplified and fed into

the input of comparator. In the Man-mode, the error amplifier compares the variation of manual voltage to a fixed reference voltage. Variation of modulation waveform with time is given in Figure 3, a : signal delivered from master clock IC1 ;b : triangular signal and DC signal from IC7 or IC8 applied to the input of comparator IC5 ;c : modulation waveform from the output comparator IC5 (duty cycle 25 %) ;d : modulation waveform from the output comparator IC5 (duty cycle 75 %).



Fig. 3 Variation of modulation waveform with the time

Gate function, the and gate IC4 allows gating of all operating modes with external T. T. L signal that is connected to J2.

#### **3 Experimental result**

Using the All-metal CO<sub>2</sub> laser mading by ourselve here, measurement of out put laser power have been made for a variety of values of duty cycle and variety of values of DC control voltage with control frequency  $(f_c)$  fixed. The results are

shown in Figure 5. The power measurement were made with a laser power meter (power wizard  $^{TM}$  250) and RF power under near perfect impedance matching condition. For duty cycle greather than 50 %, water cooling is strongly recommended. The schematic diagram of the experimental is given in Figure 4. Figure 5a shows laser output power vary proportionally with duty cycle and Figure 5b shows the variation of output power with DC control voltage, the power is proportional to voltage applied, and rising to maximum 13W and still constant. In the other hand, we have got the similar results when  $f_c = 10$ kHz.



Fig. 4 Schematic diagram of the experimental

Λ

#### 16 14 f = 5 k Hz12 power(W) 12 Dower(W) 10 10 8642 8 2 0 0 20 40 60 80 100 2 8 4 6 voltage(V) duty cycle(%)



The manually or remotely set power level can be gated by an external T. T. L signal. The controller also provide tickle level that keeps the plasma preionized to achieve fastest possible response. For typical applications of the laser for example as marking or cutting<sup>[4,5]</sup>, an external laser PUC is required. The PUC has been designed to provide necessary control of the laser output from a remote course. The PUC control laser average power by providing a variable duty cycle 5kHz signal to the laser. Control is from 1 % to 100 % of maximum.

Conclusion



Fig. 6 PUC interconnection diagram

from a remote source. The power unit controller should be connected between the laser and the marking head as shown in Figure 6.

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